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(54) PEROVSKITE PATTERNED FILM AND PREPARATION METHOD AND APPLICATION THEREOF

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(57)**ABSTRACT**

The disclosure provides a perovskite patterned film and a preparation method and application thereof. The preparation method comprises the following steps: coating a PbX₂ precursor on a substrate, and annealing to obtain a PbX₂ film substrate; coating AY salt on the nano stamp with the pattern, and annealing to obtain an AY film nano stamp; carrying out nanoimprinting to obtain an APb(X,Y), perovskite patterned film. According to the method, the perovskite pattern is accurately constructed on the PbX2 substrate in a mode of combining contact imprinting and ion diffusion, the PbX₂/ perovskite/PbX₂ coplanar surface smooth thin film is obtained, the perovskite pattern serves as an active area, the rest PbX2 naturally serves as a wide-band-gap insulation/ inert isolation material, the residual rate of the thin film is low, and the yield is greatly improved.

